

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q87054

Yasuki KIMURA

Appln. No.: 10/529,152

Group Art Unit: 1792

Confirmation No.: 1832

Examiner: Allan W. Olsen

Filed: March 24, 2005

For: METHOD OF ETCHING CHROMIUM THIN FILM AND METHOD OF PRODUCING  
PHOTOMASK

**PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of three month(s), extending the time for responding to the Office Action of November 15, 2007 to May 15, 2008.

The statutory fee of \$1050.00 is being charged to Deposit Account No. 19-4880 via EFS Payment Screen. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

*/Alan J. Kasper/*

SUGHRUE MION, PLLC  
Telephone: (202) 293-7060  
Facsimile: (202) 293-7860

---

Alan J. Kasper  
Registration No. 25,426

WASHINGTON OFFICE

**23373**

CUSTOMER NUMBER

Date: May 15, 2008